

PTO/SB/08a (06-03)

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INFORMATION DISCLOSURE  
STATEMENT BY APPLICANT

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Sheet

1

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## Complete If Known

Application Number	10/648,927
Filing Date	August 27, 2003
First Named Inventor	Tianhong Cui, et al
Art Unit	
Examiner Name	
Attorney Docket Number	16675/97145-00

## U. S. PATENT DOCUMENTS

Examiner Initials*	Cite No. <sup>1</sup>	Document Number Number-Kind Code <sup>2</sup> (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
24		US- 5,502,667	03/26/1996	Bertin, et al	
		US- 5,563,344	10/08/1996	Kaiser, et al	
		US- 5,587,128	12/24/1996	Wilding, et al	
		US- 5,726,480	03/10/1998	Pister	
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## FOREIGN PATENT DOCUMENTS

Examiner Initials*	Cite No. <sup>1</sup>	Foreign Patent Document Country Code <sup>2</sup> Number <sup>3</sup> Kind Code <sup>5</sup> (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T <sup>6</sup>

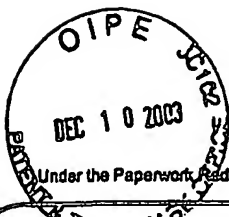
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## INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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Sheet

2

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### NON PATENT LITERATURE DOCUMENTS

Examiner Initials <sup>a</sup>	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T <sup>2</sup>
W	✓	ROOS, N., LUXBACHER, T., GILSNER, T., PFEIFFER, K., SCHULZ, H. & SCHEER, H.-C.; Nanoimprint Lithography with a Commercial 4 Inch Bond System for Hot Embossing, Presented at SPIE'S Microlithography, 27-28 February 2001, Santa Clara, CA	
	✓	HEYDERMAN, L.J., SCHIFT, H., DAVID, C., KETTERER, B., AUF DER MAUR, M. & GOBRECHT, J.; Nanofabrication Using Hot Embossing Lithography and Electroforming; Microelectronic Engineering 57-58 (2001), pgs. 375-380	
	✓	SCHEER, H.-C., SCHULTZ, H. & LYEBYEDYEV; Strategies for Wafer-Scale Hot Embossing Lithography; Proc. SPIE 4349, (2001) pg. 86	
	✓	LEE, G., CHEN, S., HUANG, G., SUNG, W. & LIN, Y.; Microfabricated Plastic Chips by Hot Embossing Methods and Their Applications for DNA Separation and Detection; Sensors and Actuators B 75 (2001), pgs. 142-148	
	✓	BECKER, H. & DIETZ, W.; Microfluidic Devices for u-TAS Applications Fabricated by Polymer Hot Embossing; SPIE Vol. 3515; Santa Clara, CA; September 1998; pgs. 177-181	
	✓	BECKER, H. & HEIM, U.; Hot Embossing as a Method for the Fabrication of Polymer High Aspect Ratio Structures; Sensors and Actuators 83 (2000) pgs. 130-135	
	✓	BECKER, H. & HEIM, U.; Silicon as Tool Material for Polymer Hot Embossing; Proceedings MEMS 99; 1999; pgs. 228-231	
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	✓	ROETTING, O., KOHLER, B., REUTHER, F., BLUM, H. & BACHER, W.; Production of Movable Metallic Microstructure by Aligned Hot Embossing and Reactive Ion Etching; Proceedings of SPIE - The International Society for Optical Engineering, Vol. 3680; pgs. 1038-1045	
W	✓	LIN, L., CHIU, C., BACHER, W. & HECKELE, M.; Microfabrication Using Silicon Mold Inserts and Hot Embossing; Proceedings of the International Symposium on Micro-Machine and Human Science; 1996; pgs. 67-71	

Examiner  
Signature

*N. P. Kumar*

Date  
Considered

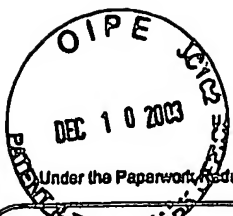
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Sheet

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**NON PATENT LITERATURE DOCUMENTS**

Examiner Initials <sup>o</sup>	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T <sup>2</sup>
2/	/	BASKI, A., ALBRECHT, T. & QUATE, C.; Tunnelling Accelerometer; Journal of Micro-Scopy, 152; pgs. 73-76, 1988	
	/	WALTMAN, S. & KAISER, W.; An Electron Tunneling Sensor; Sensors Actuators, Vol. 19; pgs. 201-210, 1989	
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	/	TANG, W., NGUYEN, T. & HOWE, R.; Laterally Driven Polysilicon Resonant Microstructures; IEEE, February 20-22, 1989, pgs. 53-59	
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	/	RODGERS, M., KOTA, S., HETRICK, J., LI, Z., JENSEN, B., KRYGOWSKI, T., MILLER, S., BARNES, S. & BURG, M.; A New Class of High Force, Low-Voltage, Compliant Actuation Systems; www.mems.sandl.gov; Albuquerque, NM	
	/	YEH, J., HUI, C. & TIEN, N.; Electrostatic Model for an Asymmetric Combedrive; Journal of Microelectromechanical Systems, Vol. 9; 2000; pgs. 126-135	
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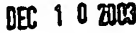
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Sheet	4	of	4		

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Examiner Signature	<i>[Signature]</i>	Date Considered	3/24/05
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